



## FPD Materials & Components Japan TC Chapter

Japan Standards Fall 2020 Meetings  
Friday, November 27, 2020  
SEMI Japan office, Tokyo, Japan  
14:00 – 17:00

### AGENDA (Tentative)

#### 1.0 Welcome / Call to Order

- 1.1 Introductions
- 1.2 Meeting Reminders (*Membership Requirement, Antitrust and Intellectual Property Reminders, Effective Meeting Guidelines*)
- 1.3 Agenda Review

#### 2.0 Review of Previous Meeting Minutes

#### 3.0 Liaison Report

- 3.1 FPD Metrology Korea TC Chapter
- 3.2 FPD Metrology Taiwan TC Chapter

#### 4.0 Staff Report

#### 5.0 Ballot Review

- 5.1 #6675: Reapproval of SEMI D9-0303 (Reapproved 0515): Terminology for FPD Substrates
- 5.2 #6584: Reapproval of SEMI D20-0706 (Reapproved 0815): Terminology for FPD Mask Defect
- 5.3 #6585: Reapproval of SEMI D21-0706 (Reapproved 0815): Terminology for FPD Mask Pattern Accuracy
- 5.4 #6633: Revision to SEMI D42-0308 (Reapproved 0815): Specification for Ultra Large Size Mask Substrate Case
- 5.5 #6634: Revision to SEMI D53-0708 (Reapproved 0815): Specification for Liquid Crystal Display (LCD) Pellicles
- 5.6 #6547: New Standard: Test method for Measurement of Water Vapor Transmission Rate for High Gas Barrier Plastic Film in a Short Time

#### 6.0 Subcommittee & Task Force Reports

- 6.1 Flexible Display TF
- 6.2 FPD Mask TF
- 6.3 FPD Materials & Components Maintenance TF

#### 7.0 Old Business

- 7.1 Project Period Review
- 7.2 5-Year Review
  - 7.2.1 SEMI D74-0116 (Guide for Measuring Dimensions of Plastic Films/Substrates)

#### 8.0 New Business



**9.0 Action Item Review**

9.1 Open Action Items

9.2 New Action Items

**10.0 Next Meeting and Adjournment**